

Brigitte Caussat

List of Publications by Year in Descending Order

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

73
papers

1,259
citations

19
h-index

33
g-index

75
ext. papers

1,401
ext. citations

5
avg. IF

4.09
L-index

| # | Paper | IF | Citations |
|----|--|------|-----------|
| 73 | Metalorganic chemical vapor deposition of aluminum oxides: A paradigm on the process-structure-properties relationship 2022 , 133-168 | | |
| 72 | An innovative kinetic model allowing insight in the moderate temperature chemical vapor deposition of silicon oxynitride films from tris(dimethylsilyl)amine. <i>Chemical Engineering Journal</i> , 2021 , 133350 | 14.7 | 0 |
| 71 | Liquid antimony pentachloride as oxidant for robust oxidative chemical vapor deposition of poly(3,4-ethylenedioxythiophene) films. <i>Applied Surface Science</i> , 2021 , 554, 149501 | 6.7 | 3 |
| 70 | Tunable SiO ₂ to SiO _x CyH films by ozone assisted chemical vapor deposition from tetraethylorthosilicate and hexamethyldisilazane mixtures. <i>Surface and Coatings Technology</i> , 2021 , 407, 126762 | 4.4 | 1 |
| 69 | An innovative GC-MS, NMR and ESR combined, gas-phase investigation during chemical vapor deposition of silicon oxynitrides films from tris(dimethylsilyl)amine. <i>Physical Chemistry Chemical Physics</i> , 2021 , 23, 10560-10572 | 3.6 | 1 |
| 68 | Network hydration, ordering and composition interplay of chemical vapor deposited amorphous silica films from tetraethyl orthosilicate. <i>Journal of Materials Research and Technology</i> , 2021 , 13, 534-547 | 5.5 | 2 |
| 67 | Beyond surface nanoindentation: Combining static and dynamic nanoindentation to assess intrinsic mechanical properties of chemical vapor deposition amorphous silicon oxide (SiO _x) and silicon oxycarbide (SiO _x Cy) thin films. <i>Thin Solid Films</i> , 2021 , 735, 138844 | 2.2 | |
| 66 | Barrier properties and hydrothermal aging of amorphous alumina coatings applied on pharmaceutical vials. <i>Surface and Coatings Technology</i> , 2021 , 425, 127711 | 4.4 | |
| 65 | An out of the box vision over oxidative chemical vapor deposition of PEDOT involving sublimed iron trichloride. <i>Synthetic Metals</i> , 2020 , 266, 116419 | 3.6 | 8 |
| 64 | Large temperature range model for the atmospheric pressure chemical vapor deposition of silicon dioxide films on thermosensitive substrates. <i>Chemical Engineering Research and Design</i> , 2020 , 161, 146-158 | 5.5 | 5 |
| 63 | Investigation of the densification mechanisms and corrosion resistance of amorphous silica films. <i>Journal of Non-Crystalline Solids</i> , 2019 , 515, 34-41 | 3.9 | 14 |
| 62 | Investigation of the initial deposition steps and the interfacial layer of Atomic Layer Deposited (ALD) Al ₂ O ₃ on Si. <i>Applied Surface Science</i> , 2019 , 492, 245-254 | 6.7 | 22 |
| 61 | In situ N ₂ -NH ₃ plasma pre-treatment of silicon substrate enhances the initial growth and restricts the substrate oxidation during alumina ALD. <i>Journal of Applied Physics</i> , 2019 , 126, 125305 | 2.5 | 2 |
| 60 | Detailed investigation of the surface mechanisms and their interplay with transport phenomena in alumina atomic layer deposition from TMA and water. <i>Chemical Engineering Science</i> , 2019 , 195, 399-412 | 4.4 | 19 |
| 59 | Computational Fluid Dynamics simulation of the ALD of alumina from TMA and H ₂ O in a commercial reactor. <i>Chemical Engineering Research and Design</i> , 2018 , 132, 795-811 | 5.5 | 19 |
| 58 | Large-scale oxidation of multi-walled carbon nanotubes in fluidized bed from ozone-containing gas mixtures. <i>Canadian Journal of Chemical Engineering</i> , 2018 , 96, 688-695 | 2.3 | 1 |
| 57 | Development of a kinetic model for the moderate temperature chemical vapor deposition of SiO ₂ films from tetraethyl orthosilicate and oxygen. <i>AIChE Journal</i> , 2018 , 64, 3958-3966 | 3.6 | 6 |

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| 56 | Effects of reducing the reactor diameter on the dense gas/solid fluidization of very heavy particles: 3D numerical simulations. <i>Chemical Engineering Research and Design</i> , 2017 , 117, 575-583 | 5.5 | 2 |
| 55 | Fluidized bed chemical vapor deposition of copper nanoparticles on multi-walled carbon nanotubes. <i>Surface and Coatings Technology</i> , 2017 , 331, 129-136 | 4.4 | 7 |
| 54 | Decoration of Carbon Nanotubes by Semiconducting or Metallic Nanoparticles using Fluidized Bed Chemical Vapour Deposition. <i>KONA Powder and Particle Journal</i> , 2016 , 33, 322-332 | 3.4 | 1 |
| 53 | Amorphous Alumina Barrier Coatings on Glass: MOCVD Process and Hydrothermal Aging. <i>Advanced Materials Interfaces</i> , 2016 , 3, 1600014 | 4.6 | 5 |
| 52 | A new route for the integration of a graphene/diazonium/PEDOT electrode towards antioxidant biomarker detection. <i>Journal of Electroanalytical Chemistry</i> , 2016 , 771, 73-79 | 4.1 | 7 |
| 51 | Modeling a MOCVD process to apply alumina films on the inner surface of bottles. <i>Surface and Coatings Technology</i> , 2015 , 275, 167-175 | 4.4 | 7 |
| 50 | Effects of reducing the reactor diameter on the fluidization of a very dense powder. <i>Powder Technology</i> , 2015 , 277, 268-274 | 5.2 | 10 |
| 49 | Iron deposition on multi-walled carbon nanotubes by fluidized bed MOCVD for aeronautic applications. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2015 , 12, 861-868 | | 2 |
| 48 | Fluidized-Bed Chemical Vapor Deposition of Silicon on Very Dense Tungsten Powder. <i>Chemical Engineering and Technology</i> , 2015 , 38, 1254-1260 | 2 | 1 |
| 47 | Silicon coating on very dense tungsten particles by fluidized bed CVD for nuclear application. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2015 , 212, 1599-1606 | 1.6 | 4 |
| 46 | Liquid and Solid Precursor Delivery Systems in Gas Phase Processes. <i>Recent Patents on Materials Science</i> , 2015 , 8, 91-108 | 0.3 | 11 |
| 45 | The Role of the Gas Phase in Graphene Formation by CVD on Copper. <i>Chemical Vapor Deposition</i> , 2014 , 20, 51-58 | | 15 |
| 44 | Amorphous Alumina Coatings on Glass Bottles Using Direct Liquid Injection MOCVD for Packaging Applications. <i>Advances in Science and Technology</i> , 2014 , 91, 117-122 | 0.1 | 5 |
| 43 | Three dimensional graphene synthesis on nickel foam by chemical vapor deposition from ethylene. <i>Materials Science and Engineering B: Solid-State Materials for Advanced Technology</i> , 2014 , 179, 12-16 | 3.1 | 25 |
| 42 | Synthesis of Multi-Walled Carbon Nanotubes by Fluidized-Bed Chemical Vapor Deposition over Co/Al ₂ O ₃ . <i>Journal of Chemical Engineering of Japan</i> , 2014 , 47, 28-39 | 0.8 | 1 |
| 41 | High quality graphene synthesized by atmospheric pressure CVD on copper foil. <i>Surface and Coatings Technology</i> , 2013 , 230, 87-92 | 4.4 | 22 |
| 40 | Fluidization and coating of very dense powders by Fluidized Bed Chemical Vapour Deposition. <i>Chemical Engineering Research and Design</i> , 2013 , 91, 2477-2483 | 5.5 | 7 |
| 39 | Decorated carbon nanotubes by silicon deposition in fluidized bed for Li-ion battery anodes. <i>Chemical Engineering Research and Design</i> , 2013 , 91, 2491-2496 | 5.5 | 5 |

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| 38 | Alumina coatings on silica powders by Fluidized Bed Chemical Vapor Deposition from aluminium acetylacetonate. <i>Chemical Engineering Journal</i> , 2012 , 211-212, 68-76 | 14.7 | 19 |
| 37 | Low temperature silicon oxide deposition on polymer powders in a fluidized bed coupled to a cold remote plasma. <i>Surface and Coatings Technology</i> , 2012 , 206, 4814-4821 | 4.4 | 6 |
| 36 | Alumina coating on dense tungsten powder by fluidized bed metal organic chemical vapour deposition. <i>Journal of Nanoscience and Nanotechnology</i> , 2011 , 11, 8083-8 | 1.3 | 5 |
| 35 | Fluidized bed chemical vapor deposition of silicon on carbon nanotubes for Li-ion batteries. <i>Journal of Nanoscience and Nanotechnology</i> , 2011 , 11, 8392-5 | 1.3 | 2 |
| 34 | Multi-scale modelling of silicon nanocrystal synthesis by Low Pressure Chemical Vapor Deposition. <i>Thin Solid Films</i> , 2011 , 519, 7650-7658 | 2.2 | 8 |
| 33 | Local Kinetic Modeling of Aluminum Oxide Metal-Organic CVD From Aluminum Tri-isopropoxide. <i>Chemical Vapor Deposition</i> , 2011 , 17, 181-185 | | 14 |
| 32 | Modeling of Silicon CVD into Agglomerates of Sub-micrometer-size Particles in a Fluidized Bed. <i>Chemical Vapor Deposition</i> , 2011 , 17, 305-311 | | 3 |
| 31 | Mechanical and Surface Properties of Chemical Vapor Deposited Protective Aluminium Oxide Films on TA6V Alloy. <i>Advances in Science and Technology</i> , 2010 , 66, 66-73 | 0.1 | 4 |
| 30 | Fluidized-Bed MOCVD of Bi ₂ O ₃ Thin Films from Bismuth Triphenyl under Atmospheric Pressure. <i>Chemical Vapor Deposition</i> , 2010 , 16, 123-126 | | 8 |
| 29 | Chemical vapor deposition of silicon nanodots on TiO ₂ submicronic powders in vibrated fluidized bed. <i>Materials Science and Engineering B: Solid-State Materials for Advanced Technology</i> , 2010 , 170, 41-50 ^{3.1} | | 8 |
| 28 | An original growth mode of MWCNTs on alumina supported iron catalysts. <i>Journal of Catalysis</i> , 2009 , 263, 345-358 | 7.3 | 53 |
| 27 | Kinetic modeling study of carbon nanotubes synthesis by fluidized bed chemical vapor deposition. <i>AIChE Journal</i> , 2009 , 55, 465-474 | 3.6 | 14 |
| 26 | Kinetic study of carbon nanotubes synthesis by fluidized bed chemical vapor deposition. <i>AIChE Journal</i> , 2009 , 55, 450-464 | 3.6 | 36 |
| 25 | Multifluid Eulerian modelling of a silicon Fluidized Bed Chemical Vapor Deposition process: Analysis of various kinetic models. <i>Chemical Engineering Journal</i> , 2009 , 148, 506-516 | 14.7 | 22 |
| 24 | Silicon Chemical Vapor Deposition on macro and submicron powders in a fluidized bed. <i>Powder Technology</i> , 2009 , 190, 185-191 | 5.2 | 20 |
| 23 | High temperature annealing of micrometric Zn ₂ SiO ₄ :Mn phosphor powders in fluidized bed. <i>Materials Research Bulletin</i> , 2008 , 43, 2751-2762 | 5.1 | 18 |
| 22 | Properties of Membranes Containing Semi-dispersed Carbon Nanotubes. <i>Environmental Engineering Science</i> , 2008 , 25, 565-576 | 2 | 83 |
| 21 | Development of an original model for the synthesis of silicon nanodots by Low Pressure Chemical Vapor Deposition. <i>Chemical Engineering Journal</i> , 2008 , 140, 600-608 | 14.7 | 4 |

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| 20 | Multifluid Eulerian modeling of dense gas-solids fluidized bed hydrodynamics: Influence of the dissipation parameters. <i>Chemical Engineering Science</i> , 2008 , 63, 5540-5551 | 4.4 | 115 |
| 19 | Modeling of spray pyrolysis—why are the synthesized Y ₂ O ₃ microparticles hollow?. <i>AIChE Journal</i> , 2008 , 54, 394-405 | 3.6 | 10 |
| 18 | Influence of the synthesis conditions of silicon nanodots in an industrial low pressure chemical vapor deposition reactor. <i>Applied Surface Science</i> , 2008 , 254, 2927-2933 | 6.7 | 1 |
| 17 | Y ₂ O ₃ :Eu micronic particles synthesised by spray pyrolysis: Global modelling and optimisation of the evaporation stage. <i>Chemical Engineering and Processing: Process Intensification</i> , 2008 , 47, 731-743 | 3.7 | 8 |
| 16 | Catalytic Production of Carbon Nanotubes by Fluidized-Bed CVD. <i>Chemical Vapor Deposition</i> , 2007 , 13, 447-457 | | 69 |
| 15 | CVD and Powders: A Great Potential to Create New Materials. <i>Chemical Vapor Deposition</i> , 2007 , 13, 443-445 | | 19 |
| 14 | Silicon CVD on powders in fluidized bed: Experimental and multifluid Eulerian modelling study. <i>Surface and Coatings Technology</i> , 2007 , 201, 8919-8923 | 4.4 | 22 |
| 13 | Towards multiscale modeling of Si nanocrystals LPCVD deposition on SiO ₂ : From ab initio calculations to reactor scale simulations. <i>Surface and Coatings Technology</i> , 2007 , 201, 8854-8858 | 4.4 | 2 |
| 12 | A dimensionless study of the evaporation and drying stages in spray pyrolysis. <i>Computers and Chemical Engineering</i> , 2007 , 31, 1088-1099 | 4 | 9 |
| 11 | A parametric study of the large scale production of multi-walled carbon nanotubes by fluidized bed catalytic chemical vapor deposition. <i>Carbon</i> , 2007 , 45, 624-635 | 10.4 | 67 |
| 10 | Crystallization of microscopic Y ₂ O ₃ powders by different techniques of fluidization at high temperature. <i>Chemical Engineering Journal</i> , 2006 , 125, 25-33 | 14.7 | 8 |
| 9 | Principles and applications of CVD powder technology. <i>Materials Science and Engineering Reports</i> , 2006 , 53, 1-72 | 30.9 | 120 |
| 8 | Experimental study on fluidization of micronic powders. <i>Powder Technology</i> , 2005 , 157, 114-120 | 5.2 | 37 |
| 7 | Modelling of an industrial moving belt chemical vapour deposition reactor forming . <i>Chemical Engineering Science</i> , 2005 , 60, 5331-5340 | 4.4 | 7 |
| 6 | Influence of dopant concentration and type of substrate on the local organization of low-pressure chemical vapour deposition in situ boron doped silicon films from silane and boron trichloride. <i>Thin Solid Films</i> , 2004 , 446, 218-226 | 2.2 | 5 |
| 5 | Carbon nanotubes produced by fluidized bed catalytic CVD: first approach of the process. <i>Chemical Engineering Science</i> , 2003 , 58, 4475-4482 | 4.4 | 127 |
| 4 | LP-CVD Silicon-Based Film Formation in Submicrometer Trenches in Industrial Equipment: Experiments and Simulation. <i>Chemical Vapor Deposition</i> , 2002 , 8, 213-219 | | 1 |
| 3 | Low-Pressure Chemical Vapor Deposition of Semi-insulating Polycrystalline Silicon Thin Films: I. Experimental Study and Proposal of New Kinetic Laws. <i>Journal of the Electrochemical Society</i> , 2001 , 148, C149 | 3.9 | 4 |

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| 2 | Boron-Doped Polysilicon: Growth Kinetics and Structural Study of Low-Pressure Chemical Vapour Deposited Films in the Case of High Doping Levels. <i>Solid State Phenomena</i> , 2001 , 80-81, 59-64 | 0.4 | 1 |
| 1 | Silicon deposition from silane or disilane in a fluidized bedPart I: Experimental study. <i>Chemical Engineering Science</i> , 1995 , 50, 3615-3624 | 4.4 | 52 |